

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L1	10844	spatial with modulator\$2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:37
2	BRS	L2	1638261	semiconduct\$4 or semi-conduct\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:39
3	BRS	L3	324421	electro-static\$5 or electrostatic\$5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:39
4	BRS	L4	912	1 and 2 and 3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:40
5	BRS	L5	457244	reset\$4 or re-set\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:40
6	BRS	L6	205	4 and 5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:41
7	BRS	L7	10058	micro-mirror\$3 or micromirror\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:41
8	BRS	L8	143	6 and 7	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 19:41
9	BRS	L10	0	("2005/0225834").URPN.	USPAT	2005/12/ 22 19:44

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	Type	L #	Hits	Search Text	DBs	Time Stamp
10	BRS	L9	429	(4 and 7) not 8	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 21:10
11	BRS	L11	3060	359/290-292,295,298,223,224.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 21:11
12	BRS	L12	1371	3 and 11	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 21:11
13	BRS	L13	1374	11not 12	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 21:11
14	BRS	L14	1689	11 not 12	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2005/12/ 22 21:11

	Document ID	1	Kind Codes	Source	Issue Date	Pages	Title
1	US 20050099670 A1	X		US - PG PUB	20050512	36	Reflection-type light modulating array element and exposure apparatus
2	US 20020176150 A1	X		US - PG PUB	20021128	31	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements
3	US 20020122239 A1	X		US - PG PUB	20020905	31	Reflective spatial light modulator with deflectable elements formed on a light transmissive substrate
4	US 20020051053 A1	X		US - PG PUB	20020502	15	Induction charge mirror
5	US 6798561 B2	X		US PAT	20040928	33	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements
6	US 6690502 B2	X		US PAT	20040210	30	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements
7	US 6538800 B2	X		US PAT	20030325	31	Reflective spatial light modulator with deflectable elements formed on a light transmissive substrate
8	US 6525759 B2	X		US PAT	20030225	15	Induction charge mirror

	Abstract	Current OR	Current XRef
1		359/291	
2		359/291	359/292; 359/293; 359/295
3		359/291	359/290; 359/292; 359/295
4		347/239	348/771
5		359/291	359/295
6		359/291	359/223; 359/295; 359/298
7		359/291	359/223; 359/295; 359/298
8		347/239	347/255

	Document ID	1	Kind Codes	Source	Issue Date	Pages	Title
9	US 6356378 B1	X		US PAT	20020312	31	Double substrate reflective spatial light modulator
10	US 6172797 B1	X		US PAT	20010109	32	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements
11	US 6046840 A	X		US PAT	20000404	31	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements
12	US 5835256 A	X		US PAT	19981110	16	Reflective spatial light modulator with encapsulated micro-mechanical elements
13	US 20050214976 A1	X		US - PG PUB	20050929	34	Methods for depositing, releasing and packaging micro-electromechanical devices on wafer substrates
14	US 20050213190 A1	X		US - PG PUB	20050929	20	Micromirror having reduced space between hinge and mirror plate of the micromirror
15	US 20050200939 A1	X		US - PG PUB	20050915	15	Micromirror modulation method and digital apparatus with improved grayscale
16	US 20050196896 A1	X		US - PG PUB	20050908	23	Micromirror array device

	Abstract	Current OR	Current XRef
9		359/291	359/223; 359/295; 359/298
10		359/291	359/223; 359/295; 359/298
11		359/291	359/223; 359/295; 359/298
12		359/291	359/295
13		438/107	
14		359/291	
15		359/290	
16		438/104	

	Document ID	1	Kind Codes	Source	Issue Date	Pages	Title
17	US 20050094244 A1	X		US - PG PU B	200505 05	17	INTEGRATED DRIVER FOR USE IN DISPLAY SYSTEMS HAVING MICROMIRRORS
18	US 20050094240 A1	X		US - PG PU B	200505 05	20	Micromirror and post arrangements on substrates
19	US 20050088719 A1	X		US - PG PU B	200504 28	20	Micromirror having reduced space between hinge and mirror plate of the micromirror
20	US 20050074919 A1	X		US - PG PU B	200504 07	25	Methods for depositing, releasing and packaging micro- electromechanical devices on wafer substrates
21	US 20050018091 A1	X		US - PG PU B	200501 27	25	Micromirror array device with a small pitch size
22	US 20040233505 A1	X		US - PG PU B	200411 25	11	Multiple hinge MEMS device
23	US 20040191946 A1	X		US - PG PU B	200409 30	23	Novel sacrificial layers for use in fabrications of microelectromechanical devices

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17		359/291	
18		359/290	
19		359/290	
20		438/107	
21		348/771	
22		359/291	
23		438/57	438/70

	Document ID	1	Kind Codes	Source	Issue Date	Pages	Title
24	US 20040190112 A1	X		US - PG PU B	200409 30	11	Optical materials in packaging micromirror devices
25	US 20040156090 A1	X		US - PG PU B	200408 12	19	High angle micro-mirrors and processes
26	US 20040125347 A1	X		US - PG PU B	200407 01	24	Micromirrors and off-diagonal hinge structures for micromirror arrays in projection displays
27	US 20040100680 A1	X		US - PG PU B	200405 27	35	Spatial light modulators with light absorbing areas
28	US 20040012838 A1	X		US - PG PU B	200401 22	38	Spatial light modulators with light blocking and absorbing areas
29	US 20040008402 A1	X		US - PG PU B	200401 15	20	Micromirrors with mechanisms for enhancing coupling of the micromirrors with electrostatic fields
30	US 20030214639 A1	X		US - PG PU B	200311 20	26	Micromirrors with OFF-angle electrodes and stops

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24		359/291	
25		359/291	
26		353/98	
27		359/291	
28		359/291	
29		359/291	
30		353/98	

	Document ID	1	Kind Codes	Source	Issue Date	Pages	Title
31	US 20030134449 A1	X		US - PG PU B	20030717	11	Method for adjusting a micro-mechanical device
32	US 20030054588 A1	X		US - PG PU B	20030320	27	Methods for depositing, releasing and packaging micro-electromechanical devices on wafer substrates
33	US 20030016435 A1	X		US - PG PU B	20030123	48	Method of manufacturing spatial light modulator and electronic device employing it
34	US 20020196524 A1	X		US - PG PU B	20021226	41	Deflectable micromirrors with stopping mechanisms
35	US 20020122894 A1	X		US - PG PU B	20020905	8	Separating wafers coated with plastic films
36	US 6952301 B2	X		US PA T	20051004	38	Spatial light modulators with light blocking and absorbing areas
37	US 6529310 B1	X		US PA T	20030304	26	Deflectable spatial light modulator having superimposed hinge and deflectable element
38	US 6452712 B2	X		US PA T	20020917	46	Method of manufacturing spatial light modulator and electronic device employing it

	Abstract	Current OR	Current XRef
31		438/52	438/455; 438/460
32		438/107	
33		359/295	359/290; 359/291; 359/292
34		359/291	
35		427/558	427/407.1; 427/58
36		359/291	359/224; 359/295; 359/298
37		359/291	359/223; 359/295
38		359/291	353/31; 353/37; 359/292; 359/295

	Document ID	1	Kind Codes	Source	Issue Date	Pages	Title
39	US 6396619 B1	X		US PAT	20020528	26	Deflectable spatial light modulator having stopping mechanisms
40	US 6271955 B1	X		US PAT	20010807	46	Method of manufacturing spatial light modulator and electronic device employing it

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39		359/291	
40		359/291	359/290; 359/292; 359/295